



Development of Thin Film Silicon Solar Cell Using Inkjet Printed Silicon and Other Inkjet Processes

Cooperative Research and Development Final Report

CRADA Number: CRD-07-260

NREL Technical Contact: Bhushan Sopori

NREL is a national laboratory of the U.S. Department of Energy, Office of Energy Efficiency & Renewable Energy, operated by the Alliance for Sustainable Energy, LLC.

CRADA Report NREL/TP-7A10-53846 April 2012

Contract No. DE-AC36-08GO28308

NOTICE

This report was prepared as an account of work sponsored by an agency of the United States government. Neither the United States government nor any agency thereof, nor any of their employees, makes any warranty, express or implied, or assumes any legal liability or responsibility for the accuracy, completeness, or usefulness of any information, apparatus, product, or process disclosed, or represents that its use would not infringe privately owned rights. Reference herein to any specific commercial product, process, or service by trade name, trademark, manufacturer, or otherwise does not necessarily constitute or imply its endorsement, recommendation, or favoring by the United States government or any agency thereof. The views and opinions of authors expressed herein do not necessarily state or reflect those of the United States government or any agency thereof.

Available electronically at http://www.osti.gov/bridge

Available for a processing fee to U.S. Department of Energy and its contractors, in paper, from:

U.S. Department of Energy Office of Scientific and Technical Information P.O. Box 62 Oak Ridge, TN 37831-0062 phone: 865.576.8401 fax: 865.576.5728 email: <u>mailto:reports@adonis.osti.gov</u>

Available for sale to the public, in paper, from:

U.S. Department of Commerce National Technical Information Service 5285 Port Royal Road Springfield, VA 22161 phone: 800.553.6847 fax: 703.605.6900 email: <u>orders@ntis.fedworld.gov</u> online ordering: <u>http://www.ntis.gov/help/ordermethods.aspx</u>

Cover Photos: (left to right) PIX 16416, PIX 17423, PIX 16560, PIX 17613, PIX 17436, PIX 17721 Printed on paper containing at least 50% wastepaper, including 10% post consumer waste.



Cooperative Research and Development Final Report

In accordance with Requirements set forth in Article XI.A(3) of the CRADA document, this document is the final CRADA report, including a list of Subject Inventions, to be forwarded to the Office of Science and Technical Information as part of the commitment to the public to demonstrate results of federally funded research.

CRADA number: CRD-07-260 (WR91)

CRADA Title: Development of Thin Film Silicon Solar Cell Using Inkjet Printed Silicon and Other Inkjet Processes

Parties to the Agreement: Silexos

Joint Work Statement Funding Table showing DOE commitment:

Estimated Costs	NREL Shared Resources	5
Year 1	\$ 00	.00
Year 2	\$ 80,000	.00
Year 3	\$ 00	.00
TOTALS	\$ 80,000	.00

Abstract of CRADA work:

The cost of silicon photovoltaics (Si-PV) can be greatly lowered by developing thin-film crystalline Si solar cells on glass or an equally lower cost substrate. Typically, Si film is deposited by thermal evaporation, plasma enhanced chemical vapor deposition, and sputtering. NREL and Silexos have worked under a CRADA to develop technology to make very low cost solar cells using liquid organic precursors. Typically, cyclopentasilane (CPS) is deposited on a glass substrate and then converted into an a-Si film by UV polymerization followed by low-temperature optical process that crystallizes the amorphous layer. This technique promises to be a very low cost approach for making a Si film.

Summary of Research Results:

Because CPS is a pyrophoric material, this work has to be done is a highly controlled ambient of very low oxygen and moisture, in a glove box. CPS is a thin monomer that does not like to stick to glass and, even when it does, it is extremely difficult to make 1 μ m or thicker films. We were able to overcome these difficulties and we were able to make thick films of crystallized silicon. We also studied methods to make heterojunctions devices.

A number of large-area, thick films were prepared by applying principles interface engineering to study effect of interface roughness on the adhesion of the amorphous silicon film. The films ranged between 1 μ m and 6 μ m in thickness. We were also able to convert these thick a-Si films into small grain crystalline films. We also successfully prepared ZnO:Al/(n)Si heterojunctions. These devices have shown record high open circuit voltages. Fully finished cells were not made.

Subject Inventions listing:

ROI-10-24: Thin Film Heterojunction Silicon Solar Cells

Report Date: 2/21/12 Responsible Technical Contact at Alliance/NREL: Bhushan Sopori

This document contains NO confidential, protectable, or proprietary information.